

FORM PTO-1449 (REV. 6-89) INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office	Attorney's Docket No. 4765	Serial No. 09/502,534
	Applicant Dan Meisburger, et al.		
	Filing Date 2/10/00	Group Art Unit 2878	

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
ken	A	3 7 9 5 8 0 9	03/05/74	Takashima	1	1	
	B	3 8 0 9 8 9 9	5/7/74	Baker et al.	1	1	
	C	3 8 4 5 3 0 5	10/29/74	Liebl	1	1	
	D	4 1 0 1 7 7 1	07/18/78	Hofer et al.	1	1	
	E	4 2 4 7 2 0 3	01/27/81	Levy et al.	1	1	
	F	4 3 6 2 9 4 2	12/07/82	Yasuda	1	1	
	G	4 4 3 8 3 3 2	03/20/84	Lichtenegger	1	1	
	H	4 5 0 3 3 2 9	03/05/85	Yamaguchi et al.	1	1	
	I	4 5 0 8 9 6 8	04/02/85	Kobayashi et al.	1	1	
	J	4 6 0 9 8 0 9	09/02/86	Yamaguchi et al.	1	1	
ken	K	4 6 1 8 9 3 8	10/21/86	Sandland et al.	1	1	

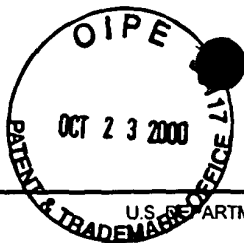
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	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER k. Nguyen	DATE CONSIDERED 03-05-07
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len	L	4 6 4 4 1 7 2	02/17/87	Sandland et al.	—	—	
	M	4 6 5 8 1 3 6	04/14/87	Ohtaka et al.	—	—	
	N	4 6 5 8 1 3 8	04/14/87	Koike et al.	—	—	
	O	4 6 6 5 3 1 5	05/12/87	Bacchetti et al.	—	—	
	P	4 7 1 4 8 3 3	12/22/87	Rose et al.	—	—	
	Q	4 7 6 9 5 4 3	09/06/88	Plies	—	—	
	R	4 8 0 5 1 2 3	02/14/89	Specht et al.	—	—	
	S	4 8 1 2 6 5 1	3/14/89	Feuerbaum et al.	—	—	
	T	4 8 1 4 6 1 5	03/21/89	Fushimi et al.	—	—	
	U	4 8 1 8 8 8 5	04/04/89	Davis et al.	—	—	
len	V	4 8 3 1 2 6 6	05/16/89	Frosien et al.	—	—	

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EXAMINER	len. Nguyen	DATE CONSIDERED	03-05-01
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EN	W	4 8 4 5 5 5 8	07/4/89	Tsai et al.	—	1	
	X	4 8 6 8 3 9 5	09/19/89	Kasahara et al.	1	1	
	Y	4 8 7 1 9 1 1	10/03/89	Van Gorkom et al.	—	1	
	Z	4 8 9 6 0 3 6	01/23/90	Rose et al.	1	1	
	AA	4 9 2 4 1 0 4	05/08/90	Stengl et al.	1	1	
	BB	4 9 2 6 4 8 7	05/15/90	Yoshida et al.	1	1	
	CC	4 9 2 6 4 8 9	05/15/90	Danielson et al.	1	1	
	DD	4 9 3 3 5 6 5	06/12/90	Yamaguchi et al.	1	1	
	EE	4 9 3 9 3 6 4	07/03/90	Ishitani et al.	1	1	
	FF	4 9 5 4 7 0 5	09/04/90	Brunner et al.	1	1	
EN	GG	4 9 5 8 0 7 4	09/18/90	Wolf et al.	1	1	

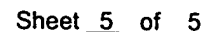
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EXAMINER	W. Nguyen	DATE CONSIDERED	03-05-01
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Patent and Trademark Office

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Applicant **Dan Meisburger, et al.**

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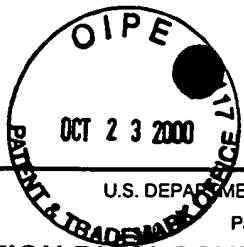
[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

kn	SS	Kato, T., et al., <u>Sub-Micron Pattern Inspection System Using Electron Beam</u> , SPIE Vol. 632 Electron-Beam, X-Ray & Ion-Beam Techniques for Submicrometer Lithographies V (1986), pp. 203-209
kn	TT	Takeuchi, S., et al., <u>Electron-Beam Inspection Technology for X-Ray Masks</u> , J. Vac. Sci. Technol. B, Vol 6, No. 1, Jan/Feb 1988
kn	UU	Goto, E., et al., <u>In-Lens Deflection System With Nonequisected-type Multipole Electrostatic Deflectors</u> , J. Vac. Sci. Technol. B 1(4), Oct-Dec. 1983, pp. 1289-1292
kn	VV	Idesawa, M., et al., <u>Numerical Considerations on Multipole-type Electrostatic Deflectors</u> , J. Vac. Sci. Technol. B 1(4), Oct – Dec. 1983, pp. 1322-1326

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len	HH	5 1 1 7 1 1 1	05/26/92	Nakamura et al.	—	—	
	II	5 1 1 8 9 4 1	06/02/92	Larson	—	—	
	JJ	5 1 2 2 6 6 3	06/16/92	Chang et al.	—	—	
	KK	5 1 4 2 1 4 8	08/25/92	Sato	—	—	
	LL	5 2 5 4 8 5 7	10/19/93	Ross et al.	—	—	
	MM	5 5 0 2 3 0 6	03/26/96	Meisburger et al.	—	—	
len	NN	5 5 7 8 8 2 1	11/26/96	Meisburger et al.	—	—	

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							Yes No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

len	OO	✓	Herriott, Donald R., et al., <u>EBES: A Practical Electron Lithographic System</u> , IEEE Transactions on Electron Devices, Vol. ED-22, No. 7, July 1975, pp. 385,392
len	PP	✓	Koshishiba, Hiroya, et al., <u>Pattern Inspection of X-Ray Mask Using Scanning Transmission Electron Microscope</u> , Japan Journal of Application Physics, Issue 12, 1989
len	QQ	✓	Andersen, W., <u>Optimum Adjustment and Correction of the Wien Filter</u> , Brit. J. Appl. Phys., 1967, Vol. 18, pp. 1573-1579
len	RR	✓	Curtis, G. H., et al., <u>A Wien Filter for Use as an Energy Analyzer with an Electron Microscope</u> , The Review of Scientific Instruments, Volume 42, Number 5, May 1971, pp. 630-637

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